



YES-CV200RFS PLASMA STRIP/DESCUM SYSTEM

Powerful Cleaning Removes Photoresist, Polyimide and BCB;
With Gentle Descum Function

SPECIFICATIONS

HARDWARE

| | |
|-----------------------------|---|
| Clean Room Compatibility | Class 10 |
| Wafer Temperature Range | Ambient to 250 °C |
| Capacity | Single wafer/pieces for 50mm - 200mm; Dual wafer/pieces for two 100mm |
| N2 Flow Rate | 1.7 SCFM |
| Process Gas Flow Rate | 20-50 SCCM average |
| Process Gas Inputs | 4 standard |
| Mass Flow Controllers | Optional, up to 4 for gas mixing |
| Interior Chamber Dimensions | 25.4 cm (W) x 28.575 cm (D) x 4.978 cm (H) — (10" x 11.25" x 1.96") |
| Hot Plate Process Area | 49 in ² maximum (200mm wafer) |
| Overall System Dimensions | 60.96 cm (W) x 109.3 cm, door open (D) x 114.3 cm (H) — (24" x 43" x 45") |
| Chamber Material | 6061-T6 aluminum |
| Compliance | SEMI S2, CE, S8 |

SOFTWARE

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|-----------------------------|--|
| Tool Control | PLC control of valves, temperature set points, plasma generation power, auto operation, touch screen interface |
| Number of Recipes | 12 with load/save/loop/link capability |
| Range of Exposure Time | 0-1200 seconds (20 minutes) |
| Resolution of Timer Setting | 1 second |

PERFORMANCE

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|------------------------------|---|
| RF Plasma Power | 40 kHz, 100 – 1000 W capacitive, downstream |
| Process Pressure Measurement | Convection type pressure sensor, 0.1 mTorr to 1000 Torr (pressure measurement sensitive to process gas composition) |
| Vent Gas Consumption | 0 SCF idle, 1.0 SCF peak, .44 SCF average |
| Reactant Gas Consumption | 0 SCF idle, 4.2 x 10 ⁻³ peak and average |
| Heat Emission | 920 watts average |
| Power Consumption with Pump | 420W idle, 2100W peak, 1210W average |
| Throughput | 1 wafer per minute (up to 200mm diameter), typically 90 seconds per wafer |
| Strip Rate | Up to 7,000 Angstroms per minute |
| Electron Shift | < 10mV electron shift in a 200A gate oxide variable plasma intensity |
| Uniformity (in wafer) | <10% |
| Cooling | Process chamber cooled by forced air convection |

ADDITIONAL

| | |
|--------------------|--------------------------------------|
| Power Requirements | 200-250V, 20 amps, 50/60 Hz, 1 phase |
| Power Supply | Automatic frequency tuning |
| System Weight | 147.42 kg (325 lbs) |

Contact Us: We offer process demonstrations. If you would like to submit samples, please call us. We can run your samples and provide a detailed process report.

Yield Engineering Systems, Inc.

Call: **1-925-373-8353** (worldwide) or **1-888-YES-3637** (US toll free)

www.yieldengineering.com